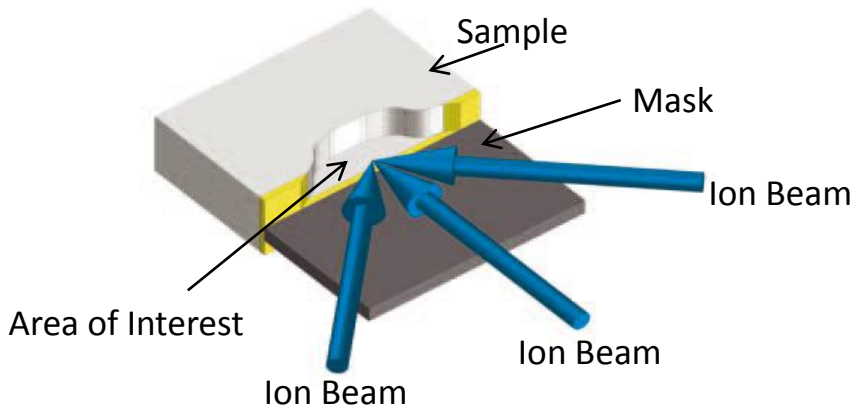
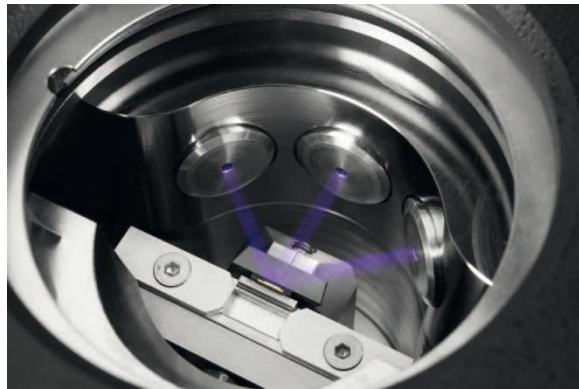


Sample Preparation for Electron Microscopy* using Ion Milling

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Friday, January 20, 2012
John Dorn Conference Room
Cook Hall 2036/2058, 10:00am



**This presentation will focus on the use of the Leica TIC3X Triple Beam Ion Miller for the preparation of samples for EBSD (stress free surface preparation), AFM and SEM analysis. Ion milling is a very useful technique for samples which are difficult to polish such as porous, multi-component, water sensitive, or composite systems. The TIC3X is now available for use in the OMM Facility. This system is complete with a cryo stage for samples which require cooling during processing.*



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